



LIST OF PUBLICATIONS CITED BY APPLICANT		<u>Atty. Docket No.</u> 0553-0323.01		<u>Serial No.</u> 10/643,690		
		<u>Applicant</u> Yoshiyuki KUROKAWA et al				
		<u>Filing Date</u> August 19, 2003		<u>Group</u> 2815		
U.S. PATENT DOCUMENTS						
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	APPLICANT	English Abstract	English Trans.	FILING DATE
OTHER PRIOR ART - NON-PATENT LITERATURE DOCUMENTS (Including Author, Title, Date, Pertinent Pages)						
988	CHU, S. et al, "The Effect of Trench-Gate-Oxide Structure on EPROM Device Operation," IEEE Electron Device Letters, vol. 9, no. 6, pp. 284-286, June (1988).					
EXAMINER: <i>J. Schenck</i>				DATE CONSIDERED: 2/7/05		
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP form. Draw line through citation if not in conformance and not considered. Include a copy of this form with the next communication to applicant.						